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520.34692V17

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: SORAOKA et al

Serial No.: 10/826,386

Filed: April 19, 2004

For: Vacuum Processing Apparatus And Semiconductor  
Manufacturing Line Using The Same

Art Unit: 3652

Examiner: T. Brahan

SUPPLEMENT RESPONSE

Mail Stop: Amendment (No Fee)  
Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

March 18, 2005

Sir:

The following amendments are respectfully requested in connection with the  
above-identified application, as listed below and as set forth on the following pages:

Amendments to the Specification; and

Remarks are included following the amendments.